

10/550384

JC20 Rec'd PCT/PTO 21 SEP 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of VENSTRA

Application No.

Examiner:

Filed: Herewith

Group Art Unit:

For: A METHOD FOR MANUFACTURING A MEMBRANE IN A (111) SURFACE
OF A (100) SILICON WAFER

PRELIMINARY AMENDMENT

Mail Stop PCT
Commissioner for Patents
P O Box 1450
Alexandria, VA 22213-1450

Sir:

INTRODUCTORY COMMENTS

Prior to the calculation of the filing fee, or examination on the merits, please amend the application identified above as follows.

Amendments to the specification begin on page 2 of this paper.

Amendments to the claims begin on page 3 of this paper.

Remarks begin on page 8 of this paper.